Institute for Ion Beam Physics and Materials Research



Titanium Oxide Layers prepared by Metal Plasma Immersion Ion Implantation and Deposition (MePIIID) as Hemocompatible Surfaces

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Motivation

Titanium oxide is known for a good bio- and hemocompatibility, but this has not yet been correlated with crystal structure or electronic properties of this semiconductor. These physical features may be interesting because surface charges interact with charges of the protein and induce conformational changes of the protein with a change of function.

Chemical oxidation of proteins on the surface is under discussion for blood clotting activation. Surfaces which prevent electron acceptance should have improved blood compatibility.

Objectives

- Synthesis of TiO2 layers with various crystal structure by MePIIID
- Modification of chemical and electronic properties by ion beam implantation.
- Investigation of the blood compatibility of the surfaces.

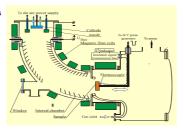
Film Deposition

Deposition of TiO₂ films with different parameters

Titanium metal plasma by cathodic arc evaporation

- arc current: 110A
- Basic vacuum 0.5 1 x 10-3 Pa
- Working Pressure 0.5 1 x 10⁻¹ Pa Deposition on oxidized Si substrates

- deposition rate 0.2-1.1µm/min
- resulting substrate temperature 25-500°C Implantation during deposition
- pulsed negative substrate bias 0, -2.5kV
- Supply of oxygen near the substrate
 - ▶ 60-180 sccm



Post Deposition Ion Beam Implantation

Phosphorous into rutile (30keV, 5 x 1015 cm-2), annealing at 900°C.

→ P is n doping element and prevents electron acceptance by the surface low dose implantation for semiconductor effects

Chromium into amorphous TiO₂ (30keV, 5 x 10¹⁷ cm⁻²) Cr has low redox potential and by this prevents

electron acceptance

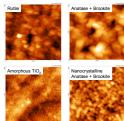
high dose implantation for chemical effects

Physical Properties

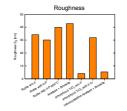
XRD reveals the following film structures

F _o [sccm]	U [kV]	T [°C]	Structure
180	-2.5	~ 450	Rutile + Anatase
60	-2.5	~ 450	Anatase + Brookite
180	0	~ 80	Amorphous TiO ₂
60	0	~ 60	Nanocrystalline Anatase + Brookite

Depending from oxygen flow and bias voltage TiO₂ layers can be obtained with different crystal structure

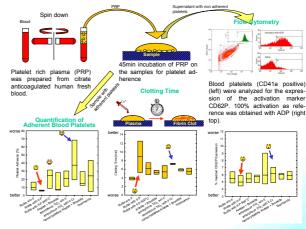






Surface roughness measured by atomic force microscopy. All samples were smooth below 50 nm, the roughness of the amorphous and nano-crystalline layers was about 1/10 of the others.

Biological Properties



platelet adhesion (median and quartiles) as indicator for increased blood clot formation.

Clotting Time as indicator for the activation of the clotting cascade. Note the effect of Cr implantation

CD62P expression as marker of activation in non-adherent platelets. Trends are the same as for platelet adherence.

Summary and Conclusions

- MePIIID is a useful technique to produce Ti based coatings with defined crystal structure.
- The effect of crystal structure of TiO_{2x} surfaces on blood compatibility is only small and could not be proven
- Ion implantation of both antioxidant elements, Cr and P, prevented activation of the clotting cascade. P implantation reduces both clotting activation and blood platelet activation and adherence, however the mechanism is unclear, as the effect disappears after annealing, what makes the electronic effect of n doping more unlikely

Literature

Tsyganov I., Maitz M.F., Wieser E., Prokert F., Richter E., Rogozin A. Structure and properties of titanium oxide layers prepared by metal plasma immersion ion implantation and deposition. <u>Surf Coat Techn</u> **174-175C**: 591-596 (2003).

Maitz M.F., Tsyganov I., Pham M.-T., Wieser E. Blood compatibility of titanium oxides with various crystal structure and element doping. J Biomater Appl 17(4): 303-320 (2003).

Contact Persons